



cket: 0756-2256

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#12/C
5/7/03
Adm H

In re Patent Application of)
Koichiro TANAKA) Group Art Unit: 2815
Serial No. 09/774,637) Examiner: J. Diaz
Filed: February 1, 2001)
For: BEAM HOMOGENIZER LASER)
IRRADIATION APPARATUS,)
SEMICONDUCTOR DEVICE,)
AND METHOD OF FABRICATING)
THE SEMICONDUCTOR DEVICE)

CERTIFICATE OF MAILING	
I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on 4.30.2003	
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AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231
Sir:

In response to the Official Action of December 31, 2002, please amend the subject application as follows:

IN THE CLAIMS:

Please add new claims 42-53 as follows:

--42. A laser irradiation apparatus for forming a laser beam elongated in one direction on an irradiated surface, comprising:

a laser oscillator; and
two reflectors for splitting said laser beam.

43. A laser irradiation apparatus of claim 42, wherein said laser beam has a length of 600 mm or more along said one direction on said irradiated surface.